

Inventor: Craig M. Carpenter; Ross S. Dando

Title: Chemical Vapor Deposition Apparatuses and Deposition  
Methods

Assignee: Micron Technology, Inc.

Attorney Docket No. MI22-1563



### INFORMATION DISCLOSURE STATEMENT

References -- See Attached Form PTO-1449

### REMARKS

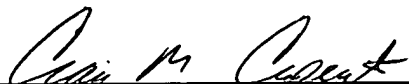
The citations listed, copies attached, may be material to the examination of the subject application and are therefore submitted in compliance with the duty of disclosure defined in 37 CFR §1.56. The Examiner is requested to make these citations of official record in this application. No admission is made regarding whether all the submitted references are prior art.

The materials cited are presented to assist in and expedite examination of this application. The present invention is considered to be patentable over the cited materials. Expeditious examination and allowance of this application as a patent are therefore urged in order that the public may benefit from the disclosure and commercialization of the invention.

**EL 465855490**

R spectfully submitted,

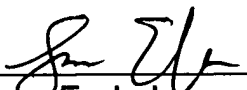
Dated: 1 MARCH 2001

Inventor:   
Craig M. Carpenter

Dated: 3 March 2001

Inventor:   
Ross S. Dando

Dated: 13 Mar 2001

Attorney:   
James E. Lake  
Reg. No.: 44,854

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. M122-1563	SERIAL NO. Filed Herewith
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT Craig M. Carpenter; Ross S. Dando	
				FILING DATE Filed Herewith	GROUP Unknown

JC936 U.S. PTO  
 09/815620  
 03/13/01

U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,983,906	11/16/99	Zhao et al			
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

FOREIGN PATENT DOCUMENTS								
		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							

OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)			
	AR		
	AS		
	AT		

EXAMINER	DATE CONSIDERED
----------	-----------------

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.